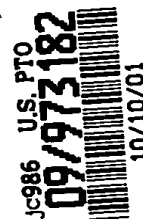


Docket No.: 50099-183

PATENT



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of :
Seiichiro OKUDA, et al. :
Serial No.: : Group Art Unit:
Filed: October 10, 2001 : Examiner:
For: SUBSTRATE PROCESSING APPARATUS

CLAIM OF PRIORITY

Commissioner for Patents
Washington, DC 20231

Sir:

In accordance with the provisions of 35 U.S.C. 119, Applicants hereby claim the priority of:

Japanese Patent Application No. 2000-313496, filed October 13, 2000

A Certified copy will be filed in due course.

Respectfully submitted,

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